

**ABSTRACT**

**Method, Computer Program Product and Apparatus for Substrate Processing**

5           A method of scheduling one or more maintenance actions in at least a part of a substrate  
processing system is provided. According to an embodiment, the method includes determining a  
gap in the flow of substrates in a part of the substrate processing system and scheduling one or  
more maintenance actions to be performed in another part of the substrate processing during a  
period associated with the gap. An increase of productivity of substrate processing can be  
10 achieved through a reduction in downtime in a substrate processing system by appropriate  
scheduling of maintenance actions.

Fig. 4